



Sheet 1 of 1

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
116-010872SERIAL NO.  
09/877,223INFORMATION DISCLOSURE STATEMENT  
STATEMENT BY APPLICANT

APPLICANT(S)

Kazuhiro HONDA

(Use several sheets if necessary)

FILING DATE  
June 8, 2001GROUP ART UNIT  
2877

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

w7	AQ	"Evaluation of an Advanced Mask Writing System", Shinji KUBO et al., <u>Part of the SPIE Symposium on Photomask and X-Ray Mask Technology VI, Yokohama, Japan, September 1999, SPIE Vol. 3748, pp. 426-435.</u>
w7	AR	"Measuring Critical Dimensions and Overlays as Prescribed by the National Technology Roadmap for Semiconductors", Syed A. Rizvi, <u>SPIE Vol. 3236, pp. 170-175.</u>
w7	AS	"Proximity Effect in Electron-Beam Lithography", T.H.P. Chang, <u>J. Vac. Sci. Technol., Vol. 12, No. 6, Nov./Dec. 1975, pp. 1271-1275.</u>

EXAMINER

DATE CONSIDERED

4-14-04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.